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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Andrej S. MITROVIC

SERIAL NO: 10/673,501

GROUP: 2128

FILED: September 30, 2003

EXAMINER: Saxena, Akash

FOR: SYSTEM AND METHOD FOR USING FIRST-PRINCIPLES SIMULATION
TO CHARACTERIZE A SEMICONDUCTOR MANUFACTURING PROCESS

LETTER

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Submitted herewith is a Chinese Office Action for the Examiner's consideration. The reference cited therein have been previously cited in the Office Action of September 26, 2006.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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